

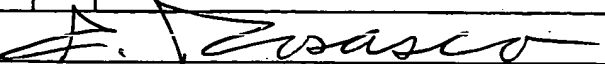


Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 244420US2		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Yukio TANIGUCHI, et al.			
				FILING DATE Herewith		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
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	AH						
	AI						
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	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	1 047 119	10/25/00	Europe			
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	Masakiyo MATSUMURA, "Preparation of Ultra-Large Grain Silicon Thin-Films by Excimer-Laser", SURFACE SCIENCE, Vol. 21, No. 5, 2000, pgs. 278-287					
	AX	Mitsuru NAKATA, et al., "A New Nucleation-Site-Control Excimer-Laser-Crystallization Method", THE JAPAN SOCIETY OF APPLIED PHYSICS, Vol. 40, Part 1, No. 5A, May 2001, pgs. 3049-3054					
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner 					Date Considered 9-8-05		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							